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2858

## U.S. PATENT DOCUMENTS

*EXAMINER INITIAL	DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE
	2003/0057977	03/2003	Werner, Jr. et al.	324	754	
	2006/0171728	08/2006	Ichimura et al.	399	48	
	2006/0186898	08/2006	Ichimura et al.	324	663	

## FOREIGN PATENT DOCUMENTS

	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION YES/NO/ OR ABSTRACT
	1 003 044 A2	05/2000	Europe			
	10044887	05/2001	Germany			Abstract

## OTHER DOCUMENT(S) (Including Author, Title, Date, Pertinent Pages, Etc.)

	Riehl, P. S., "Microsystems for Electrostatic Sensing", Dissertation, Nov. 2002, pp. 1-8, 32-40, 79-84.
	Hsu, C. H. et al., "Micromechanical Electrostatic Voltmeter", Proc. Int'l. Conf. on Solid State Sensors and Actuators, NY, IEEE, US, vol. 6, 24, June 1991, pp. 659-662

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\*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

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